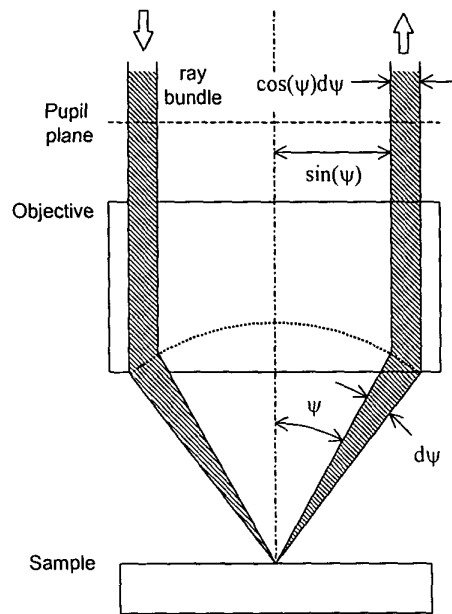
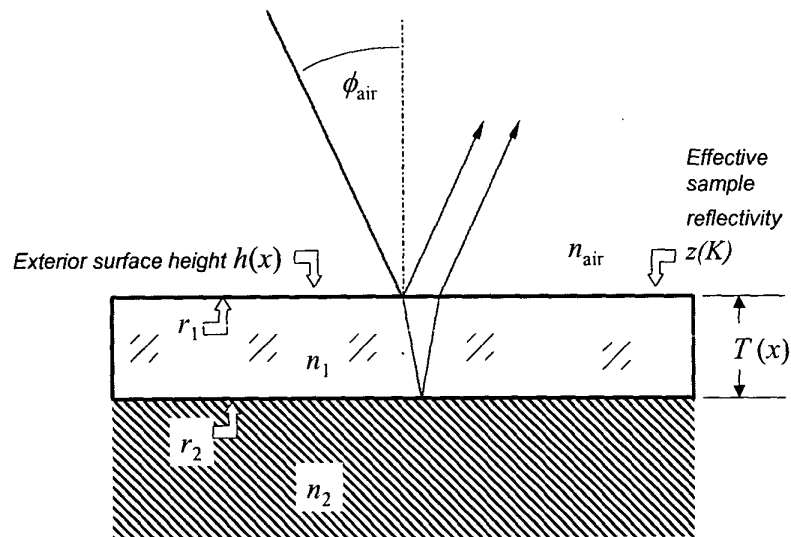
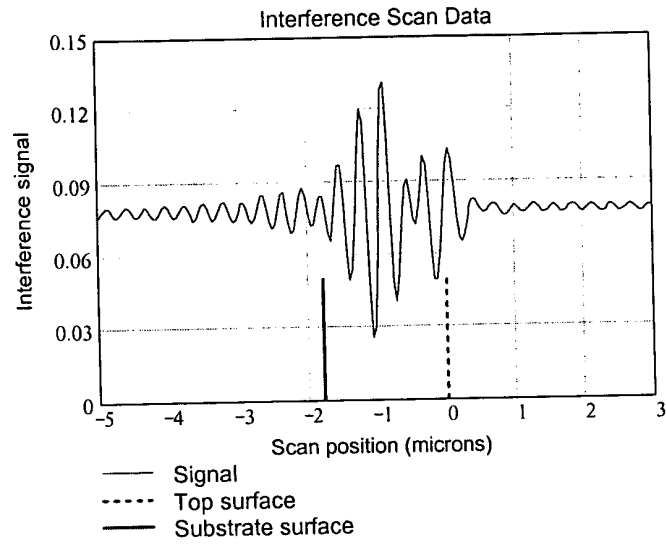
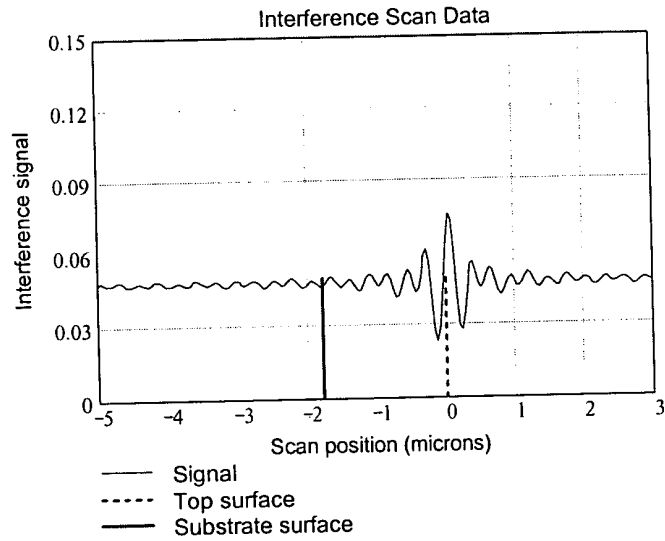


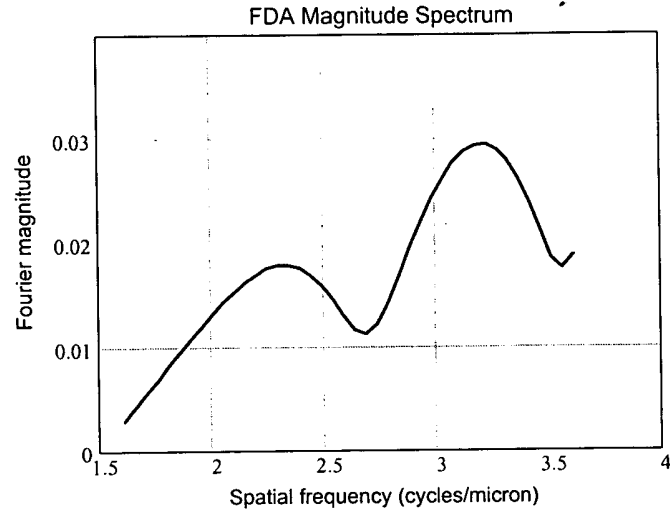
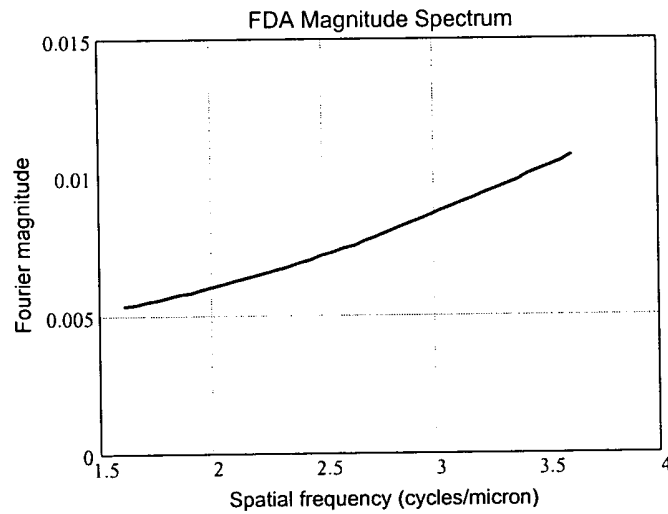
FIG. 1

**FIG. 2****FIG. 3**

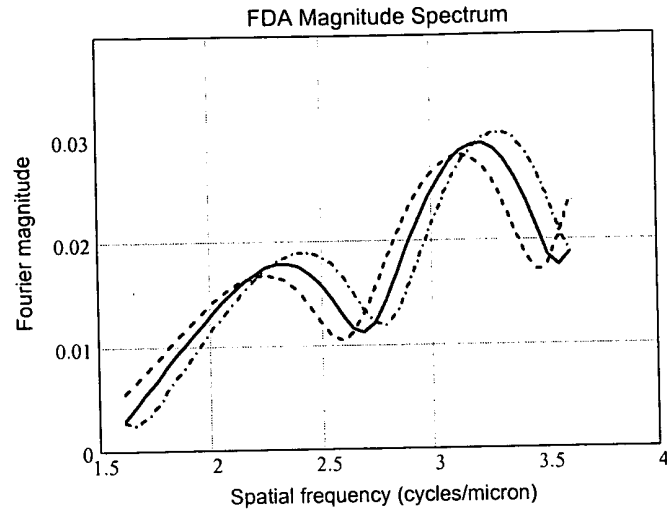
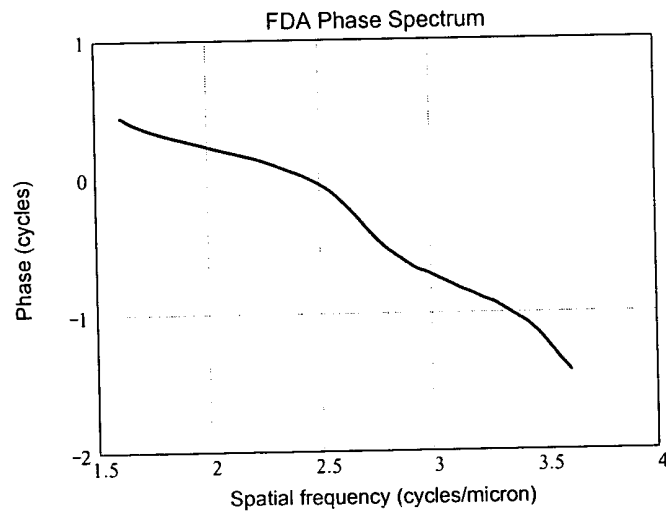
Applicant(s): Peter J. de Groot  
INTERFEROMETRY METHOD FOR ELLIPSOMETRY,  
REFLECTOMETRY, AND SCATTEROMETRY MEASUREMENTS,  
INCLUDING CHARACTERIZATION OF THIN FILM STRUCTURES

**FIG. 4****FIG. 5**

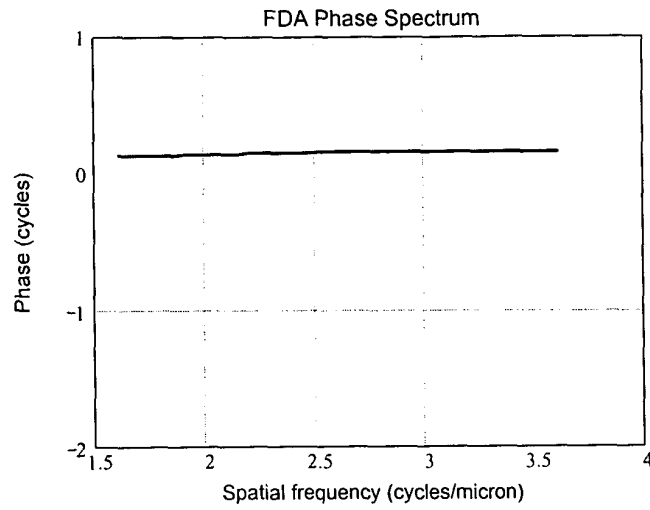
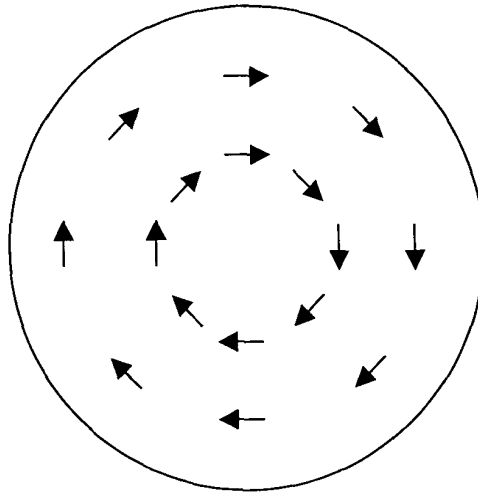
Applicant(s): Peter J. de Groot

INTERFEROMETRY METHOD FOR ELLIPSOMETRY,  
REFLECTOMETRY, AND SCATTEROMETRY MEASUREMENTS,  
INCLUDING CHARACTERIZATION OF THIN FILM STRUCTURES**FIG. 6****FIG. 7**

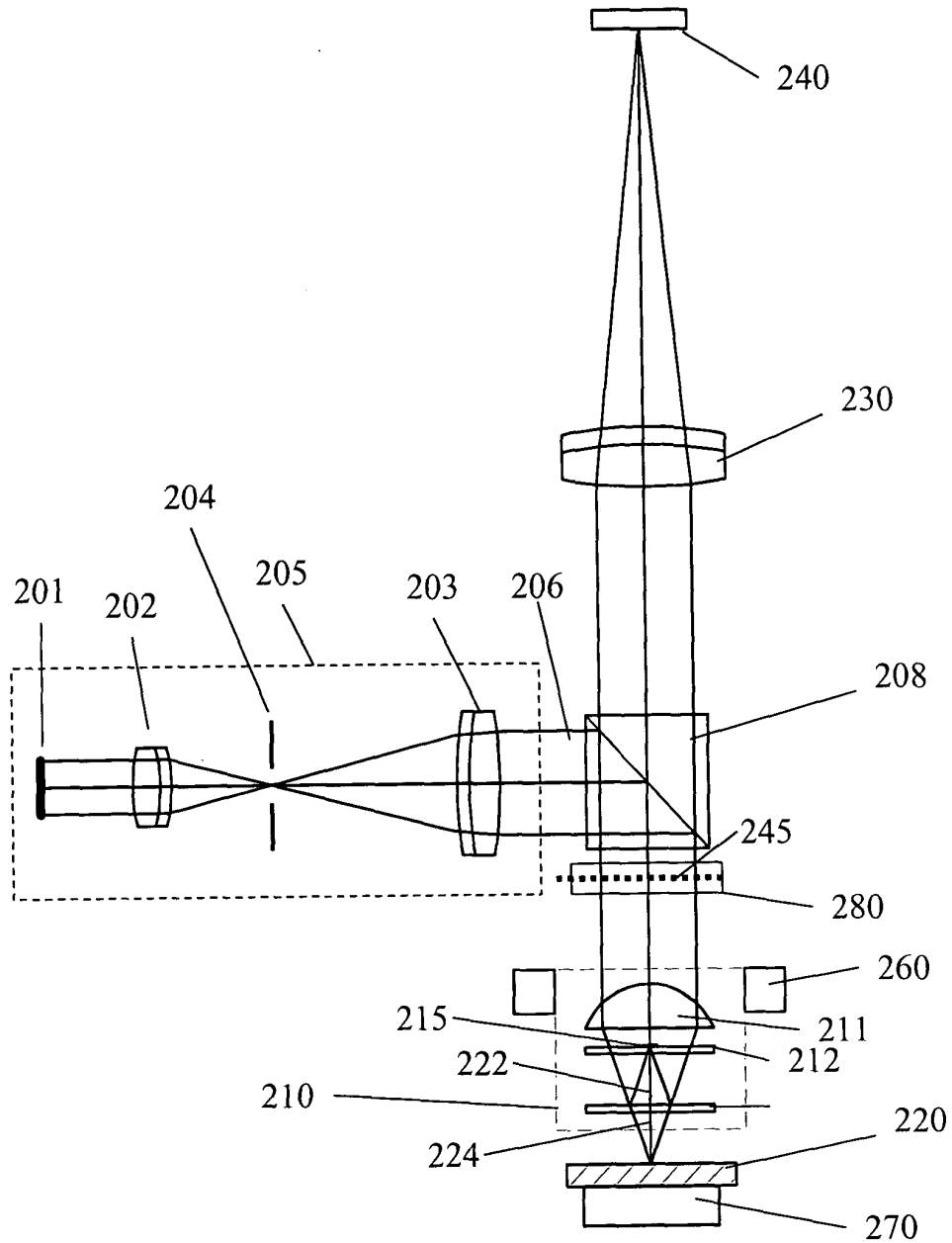
Applicant(s): Peter J. de Groot  
INTERFEROMETRY METHOD FOR ELLIPSOMETRY,  
REFLECTOMETRY, AND SCATTEROMETRY MEASUREMENTS,  
INCLUDING CHARACTERIZATION OF THIN FILM STRUCTURES

**FIG. 8****FIG. 9**

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INTERFEROMETRY METHOD FOR ELLIPSOMETRY,  
REFLECTOMETRY, AND SCATTEROMETRY MEASUREMENTS,  
INCLUDING CHARACTERIZATION OF THIN FILM STRUCTURES

**FIG. 10****FIG. 12**

Applicant(s): Peter J. de Groot

INTERFEROMETRY METHOD FOR ELLIPSOMETRY,  
REFLECTOMETRY, AND SCATTEROMETRY MEASUREMENTS,  
INCLUDING CHARACTERIZATION OF THIN FILM STRUCTURES**FIG. 11**